



FPD Materials and Components Japan TC Chapter and FPD Metrology Japan TC Chapter Joint Meeting Meeting Summary and Minutes

SEMI Japan Standards Spring 2016 Meetings

April 6, 2016, 15:00-17:00

SEMI Japan, Tokyo, Japan

TC Chapter Announcements

FPD Materials & Components Japan TC Chapter:

SEMI Japan Standards Summer 2016 Meetings

Friday, July 1, 2016, 15:00-17:00

Campus Innovation Center Tokyo, Tokyo, Japan

FPD Metrology Japan TC Chapter:

SEMI Japan Standards Fall 2016 Meetings

October, 2016 (TBD)

SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs of FPD M&C Committee: Tadahiro Furukawa (Yamagata University), Yoshi Shibahara (Fujifilm)

Co-Chairs of FPD Metrology Committee: Ryoichi Watanabe (Japan Display), Akira Kawaguchi (Otsuka Electronics)

SEMI Staff: Naoko Tejima (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Sumitomo Bakelite	Eguchi	Toshimasa	Corning International	Okamura	Haruo
Yamagata University	Furukawa	Tadahiro	Fujifilm	Shibahara	Yoshi
HOYA	Ihara	Hirofumi	Sony	Tomioka	Satoshi
Otsuka Electronics	Kawaguchi	Akira	Japan Display	Watanabe	Ryoichi
Nitto Denko	Kobayashi	Shigeo	SEMI Japan	Tejima	Naoko
Konica Minolta	Ochi	Keizo			

** alphabetical order by last name*

Table 2 Leadership Changes

FPD M&C Japan TC Chapter

<i>Group</i>	<i>Previous Leader</i>	<i>New Leader</i>
Polarizing Film Task Force Co-leaders	- Toshihito Otsuka (Sanritz) - Yoshi Shibahara (Fujifilm) - Shigeo Kobayashi (Nitto Denko)	- Toshihito Otsuka (Sanritz) - Yoshi Shibahara (Fujifilm) - Motoshige Tatsumi (Nitto Denko)

FPD Metrology Japan TC Chapter

None.

Table 3 Ballot Results

FPD M&C Japan TC Chapter

None.

FPD Metrology Japan TC Chapter

None.

Table 4 Authorized Activities
FPD M&C Japan TC Chapter

<i>Doc.#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
6011	SNARF	FPD Mask TF	Reapproval of SEMI D38-0211, Guide for Quality Area of LCD Masks <i>*TC Member Review is not required.</i>
6012	SNARF	Polarizing Film TF	Reapproval of SEMI D39-0704 (Reapproved 0710), Specification for Markers on FPD Polarizing Films <i>*TC Member Review is not required.</i>
6013	SNARF	FPD Mask TF	Reapproval of SEMI D6-0211, Specification for Liquid Crystal Display (LCD) Mask Substrates <i>*TC Member Review is not required.</i>
6014	SNARF	Polarizing Film TF	Revision to SEMI D60-0710, Test Method of Surface Scratch Resistance for FPD Polarizing Film and Its Materials <i>* TC Member Review took place before approval at the TC Chapter</i>

FPD Metrology Japan TC Chapter

None.

NOTE 1: SNARFs and TFOFs are available for review on the SEMI Web site at:
<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 5 Authorized Ballots
FPD M&C Japan TC Chapter

<i>Doc.#</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
6011	Cycle 4, 2016	FPD Mask TF	Reapproval of SEMI D38-0211, Guide for Quality Area of LCD Masks <i>*TC Member Review is not required.</i>
6012	Cycle 4, 2016	Polarizing Film TF	Reapproval of SEMI D39-0704 (Reapproved 0710), Specification for Markers on FPD Polarizing Films <i>*TC Member Review is not required.</i>
6013	Cycle 4, 2016	FPD Mask TF	Reapproval of SEMI D6-0211, Specification for Liquid Crystal Display (LCD) Mask Substrates <i>*TC Member Review is not required.</i>

FPD Metrology Japan TC Chapter

None.

Table 6 New Action Items
FPD M&C Japan TC Chapter

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C 160406-01	SEMI Staff	To submit reapproval ballot of <i>SEMI D38-0211, Guide for Quality Area of LCD Masks</i> , for Cycle 4, 2016.
FPD M&C 160406-02	SEMI Staff	To submit reapproval ballot of <i>SEMI D39-0704 (Reapproved 0710), Specification for Markers on FPD Polarizing Films</i> , for Cycle 4, 2016.
FPD M&C 160406-03	SEMI Staff	To submit reapproval ballot of <i>SEMI D6-0211, Specification for Liquid Crystal Display (LCD) Mask Substrates</i> , for Cycle 4, 2016.
FPD M&C 160406-04	Co-chairs	To submit JRSC a proposal to add "Measuring Method" as Subtype of documents to the procedural Manual by April 15.

FPD Metrology Japan TC Chapter

None.

Table 7 Previous Meeting Action Items

FPD M&C Japan TC Chapter

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C 160205-01	SEMI Staff	To submit reapproval ballot of D34-0710, Test Method for FPD Polarizing Films, for Cycle 4. ... Open
FPD M&C 160205-02	SEMI Staff	To request GCS review of revision SNARF of D60-0710, Test Method of Surface Scratch Resistance for FPD Polarizing Film and Its Materials Measuring Method of Polarizing Film Configuration after 2-weeks review by TC members. ... Close
FPD M&C 160205-03	Co-chairs	To submit a proposal about sub category title of standards to SPI. ... Close

FPD Metrology Japan TC Chapter

None.

[Common Part 1]

1 Welcome, Reminders, and Introductions

Tadahiro Furukawa, committee co-chair, called the meeting to order at 15:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2016 Calendar of Events, Global Standards Meeting Schedule, 2016 Critical Dates for SEMI Standards Ballots, A&R Ballot Review, SEMI Standards Publication, Highlights from JRSC Meeting during SEMICON Japan 2015, PPT Template Updates, and Contact Information.

Attachment: 01_SEMI_Staff_Report_160406

3 Liaison Reports

3.1 *FPD Metrology Korea TC Chapter*

Naoko Tejima reported for the FPD Metrology Korea TC Chapter. This report included Leadership, Current Committee Organization, Meeting Information, Major Updates and Contact Information

Attachment: 02_Korea_FPD_Liaison_Report_April_2016_160406

3.2 *FPD Metrology Taiwan TC Chapter*

Naoko Tejima reported for the FPD Metrology Taiwan TC Chapter. This report included Current Committee Organization, Committee Highlights, Meeting Information and Contact Information.

Attachment: 03_Taiwan_FPD_Liaison_Report_April_2016_160406

[FPD Materials and Components Japan TC Chapter Part]

4 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

It was pointed followings:

- “Yoshitada Nogami, SK Electronics” should be added to “Table 1 Meeting Attendees”
- “*Sub-category of Standards Document*” should be corrected to “*Sub-type*” in “Table 7” and “8.1”
- Delete “and submit its ballot for Cycle 4, 2016” of *Action Item* of “Table 7”

Motion: To approve the minutes of the previous meeting as written after the above points are corrected.

By / 2nd: Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)

Discussion: None

Vote: 8 in favor and 0 opposed. **Motion passed.**

Attachment: 04_JA_FPD_M+C_Previous_Mtg_Minutes_160406

5 Subcommittee and Task Force Reports

5.1 Polarizing Film Task Force

Yoshi Shibahara reported for the Polarizing Film Task Force. The following document is for 5-year review and it was already taken place 2-weeks reviewed by TC members.

- *SEMI D60-0710, Test Method of Surface Scratch Resistance for FPD Polarizing Film and Its Materials.*

Motion: To approve SNARF, *Revision to SEMI D60-0710, Test Method of Surface Scratch Resistance for FPD Polarizing Film and Its Materials.*

By / 2nd: Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)

Discussion: None.

Vote: 8 in favor and 0 opposed. **Motion passed.**

Attachment: 05_SNARF_of_Revision_to_D60_160406

The following document is also for 5-year review.

- *SEMI D39-0704 (Reapproved 0710), Specification for Markers on FPD Polarizing Films.*

Motion: To submit reapproval ballot *SEMI D39-0704 (Reapproved 0710), Specification for Markers on FPD Polarizing Films*, for Cycle 4, 2016.

By / 2nd: Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)

Discussion: None.

Vote: 8 in favor and 0 opposed. **Motion passed.**

Attachment: 06_SNARF_of_Reapproval_of_D39_160406

Action Item: SEMI to prepare reapproval SNARF of SEMI D39

Action Item: SEMI to submit reapproval ballot of D39 for Cycle 4, 2016

Shigeo Kobayashi (Nitto Denko) resigned the committee member because of personnel transfer. Motoshige Tatsumi (Nitto Denko) took over his position and was appointed as new co-leader.

Motion: To approve to change the TF leader from Shigeo Kobayashi (Nitto Denko) to Motoshige Tatsumi (Nitto Denko).

By / 2nd: Shigeo Kobayashi (Nitto Denko) / Yoshi Shibahara (Fujifilm)

Discussion: None

Vote: 8 in favor and 0 opposed. **Motion passed.**

Attachment: 07_Polarizing_TF_Report_160406

5.2 Flexible Display Task Force

Tadahiro Furukawa reported for the Flexible Display Task Force that there were no particular things should be reported.

5.3 FPD Color Filter Task Force

Tadahiro Furukawa reported for the *FPD Color Filter Task Force*. The following 3 documents are for 5-year review.

- SEMI D22-1109, Test Method for the Determination of Color, Transmittance of FPD Color Filter Assemblies.
>> needs to change References and should be changed “Test Method” to “Measurement Method”
- SEMI D55-0310, Guide for Evaluation Method of Color Performance for Color Filter Assemblies (Evaluation Method of Color Purity)
>> needs to change References
- SEMI D63-0811, Measurement Method for Depolarization Effect of FPD Color Filter
>> Sub-type “Measurement Method” is not suitable to the current regulation.

5.4 FPD Mask Task Force

Hirofumi Ihara reported for the *FPD Mask Task Force*. The following 2 documents are for 5-year review.

- *SEMI D6-0211, Specification for Liquid Crystal Display (LCD) Mask Substrates*

Motion: To submit reapproval ballot *SEMI D6-0211, Specification for Liquid Crystal Display (LCD) Mask Substrates*, for Cycle 4, 2016.

By / 2nd: Hirofumi Ihara (HOYA) / Ryoichi Watanabe (Japan Display)

Discussion: None.

Vote: 8 in favor and 0 opposed. **Motion passed.**

Attachment: 08_SNARF_of_Reapproval_of_D6_160406

Action Item: SEMI to prepare reapproval SNARF of SEMI D6

Action Item: SEMI to submit reapproval ballot of D6 for Cycle 4, 2016

- *SEMI D38-0211, Guide for Quality Area of LCD Masks*

Motion: To submit reapproval ballot *SEMI D38-0211, Guide for Quality Area of LCD Masks*, for Cycle 4, 2016.

By / 2nd: Hirofumi Ihara (HOYA) / Ryoichi Watanabe (Japan Display)

Discussion: None.

Vote: 8 in favor and 0 opposed. **Motion passed.**

Attachment: 09_SNARF_of_Reapproval_of_D38_160406

Action Item: SEMI to prepare reapproval SNARF of SEMI D38

Action Item: SEMI to submit reapproval ballot of D38 for Cycle 4, 2016

6 Old Business

6.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 8 Previous Meeting Action Items
FPD M&C Japan TC Chapter

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C 160205-01	SEMI Staff	To submit reapproval ballot of D34-0710, Test Method for FPD Polarizing Films, for Cycle 4. ... Open
FPD M&C 160205-02	SEMI Staff	To request GCS review of revision SNARF of D60-0710, Test Method of Surface Scratch Resistance for FPD Polarizing Film and Its Materials Measuring Method of Polarizing Film Configuration after 2-weeks review by TC members. ... Close
FPD M&C 160205-03	Co-chairs	To submit a proposal about sub category title of standards to SPI. ... Close

7 New Business

None.

[FPD Metrology Japan TC Chapter Part]

8 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: To approve the minutes of the previous meeting as written.

By / 2nd: Akira Kawaguchi (Otsuka Electronics) / Keizo Ochi (Konica Minolta)

Discussion: None

Vote: 9 in favor and 0 opposed. **Motion passed.**

Attachment: 10_JA_FPD_Met_Previous_Mtg_Minutes_160406

9 Subcommittee and Task Force Reports

9.1 D31 Revision Task Force

Keizo Ochi reported for the D31 Revision Task Force that there were no particular things should be reported s.

10 Old Business

None.

11 New Business

None.

[Common Part 2]

12 Discussion about the Sub-Type of Documents

It was discussed that “Measurement Method” should be added as the sub Type of documents, between SPI and Tadahiro Furukawa, co-chairs of FPD Materials and Components. It should be discussed continuously and will be proposed officially to JRSC by FPD Materials & components Japan TC chapter independently.

13 Action Item Review

13.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

14 Next Meeting and Adjournment

The next meeting of the FPD Materials and Components Japan TC Chapter is scheduled for Friday, July 1, 2016, 15:00-17:00, Campus Innovation Center Tokyo, Tokyo, Japan.

The next meeting of the FPD Metrology Japan TC Chapter is scheduled for October, 2016 (TBD), SEMI Japan, Tokyo, Japan

See <http://www.semi.org/en/events> for the current list of meeting schedules.

Having no further business, a motion was made to adjourn. Adjournment was at 17:00.



Respectfully submitted by:
Naoko Tejima
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Minutes approved by:

Tadahiro Furukawa (Yamagata University), Co-chair of FPD Materials & Components Japan TC Chapter	July 1, 2016
Yoshi Shibahara (Fujifilm), Co-chair of FPD Materials & Components Japan TC Chapter	July 1, 2016
Ryoichi Watanabe (Japan Display), Co-chair of FPD Metrology Japan TC Chapter	July 1, 2016
Akira Kawaguchi (Otsuka Electronics), Co-chair of FPD Metrology Japan TC Chapter	July 1, 2016

Table 9 Index of Available Attachments #1

#	<i>Title</i>
1	SEMI_Staff_Report_160406
2	Korea_FPD_Liaison_Report_April_2016_160406
3	Taiwan_FPD_Liaison_Report_April_2016_160406
4	JA_FPD_M+C_Previous_Mtg_Minutes_160406
5	SNARF_of_Revision_to_D60_160406
6	SNARF_of_Reapproval_D39_160406
7	Polarizing_TF_Report_160406
8	SNARF_of_Reapproval_of_D6_160406
9	SNARF_of_Reapproval_of_D38_160406
10	JA_FPD_Met_Previous_Mtg_Minutes_160406

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.